



Manufacturing Technology Trends and Implications for Design

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Process Benchmark

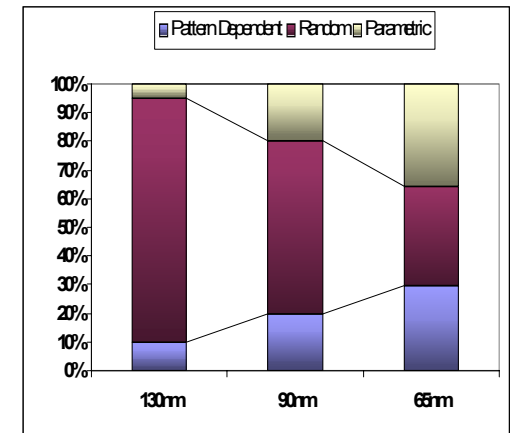
- 130nm SOC world class yields at maturity level
- 90nm SOC world class yields becoming mature
- 65nm SOC world class yields capable of early manufacturing
- **Implications:**
 - 90nm is economically attractive relative to 130nm for many logic applications
 - 65nm volume production will be here within 1 year+

65nm and Below Yield Challenges

High Yield and Performance Variability

- **Very small litho process window**
 - High risk of product to product variability
 - Equipment differences and PM cycles will have more dominant effect
- **Stress engineering create more performance variability**
 - Layout dependant stress mechanisms
 - Film control is critical
 - Modeling is more difficult
- **NiSi abnormalities will create transistor variability**

Design rules, layout design styles, and physical synthesis methods will need to embed layout consistency



Yield Loss Breakdown

Trends in Manufacturing and Implication for Design

New Optimization Variable: Good Die per Wafer

- The old paradigm - smaller is better
- The new paradigm - maximize of good die per wafer
- Examples of the new paradigm
 - Logic redundancy
 - Restricted orientations and pitches
 - Regular arrays
- Implications
 - DFM is more than doubling vias and contacts
 - Need to simulate yields across all levels of the design flow
 - Need accurate characterization of process capability over time